

EUROPEAN PATENT OFFICE

Patent Abstracts of Japan

データベース

PUBLICATION NUMBER : 11297797
PUBLICATION DATE : 29-10-99

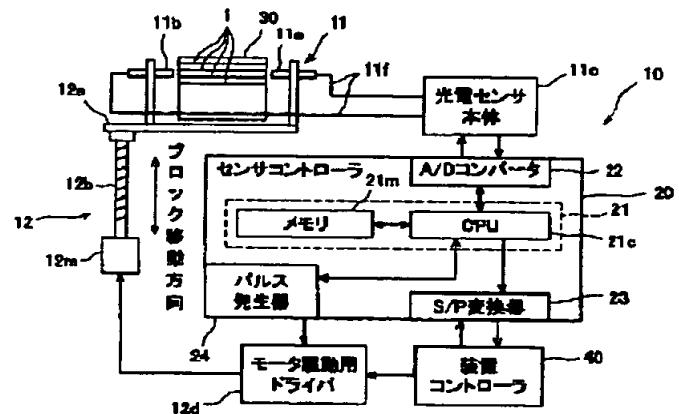
APPLICATION DATE : 10-04-98
APPLICATION NUMBER : 10099546

APPLICANT : YAMATAKE CORP;

INVENTOR : KONDO NAOMI;

INT.CL. : H01L 21/68

TITLE : WAFER-DETECTING DEVICE



ABSTRACT : PROBLEM TO BE SOLVED: To provide a wafer-detecting device for deciding not only the presence of a wafer being accommodated in a wafer carrier but also the accommodation state of the wafer.

SOLUTION: A wafer-detecting device 10 is provided with a light-projecting means 11a for projecting detection light to a wafer being accommodated in a wafer carrier, a light-receiving means 11b for detecting detection light which is projected by the light-projecting means 11a, a traveling means 12 for relatively making the light-projecting means 11a and the light-receiving means 11b more, so that they cross the outer-periphery surface of a wafer carrier 30 and for outputting the detection position information, and a deciding means 21 for deciding the accommodation state of the wafer based on state near the peak of the change in the quality of received light at each detection position due to the move, thus deciding the presence and the accommodation state of the wafer.

COPYRIGHT: (C)1999,JPO